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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/797,664	03/11/2004	Pieter Johannes Marius Van Groos	081468-0308664	3918
909 7590 04/08/2008 PILLSBURY WINTHROP SHAW PITTMAN, LLP P.O. BOX 10500 MCLEAN, VA 22102				
EXAMINER				
KIM, PETER B				
ART UNIT		PAPER NUMBER		
2851				
MAIL DATE		DELIVERY MODE		
04/08/2008		PAPER		

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Office Action Summary

Application No.

10/797,664

Applicant(s)

VAN GROOS ET AL.

Examiner

Peter B. Kim

Art Unit

2851

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --
Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☐ Responsive to communication(s) filed on ____.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-19 is/are pending in the application.
- 4a) Of the above claim(s) ____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) ____ is/are allowed.
- 6) ☒ Claim(s) 1-19 is/are rejected.
- 7) ☐ Claim(s) ____ is/are objected to.
- 8) ☐ Claim(s) ____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 11 March 2004 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
- Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
- Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☒ All b) ☐ Some * c) ☐ None of:
1. ☒ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. ____.
 3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- 1) ☒ Notice of References Cited (PTO-892)
- 2) ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)
- 3) ☒ Information Disclosure Statement(s) (PTO/SE-08)
- Paper No(s)/Mail Date 03/2004, 08/2004, 01/2008
- 4) ☐ Interview Summary (PTO-413)
- Paper No(s)/Mail Date ____
- 5) ☐ Notice of Informal Patent Application
- 6) ☐ Other: ____

DETAILED ACTION

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claims 1, 4, 5, 9 and 10 are rejected under 35 U.S.C. 102(b) as being anticipated by Nakano (2002/0024645).

Nakano discloses an assembly and a method of maintaining a machine part arranged in an interior space (9) of a machine, wherein the interior is kept at a first pressure (para 0006) and is separated from an environment (outside of chamber 9) via a load lock (14), the method characterized by transporting a machine part via the load lock out from the interior space; and transporting via the load lock into the interior space, the machine part after being maintained or a separate replacement machine part (para 0012). Nakano discloses the machine which is a lithographic projection apparatus (Fig. 1) and gripper (16) arranged to grip and release substrate. Nakano discloses the machine part (substrate) which is connected to an disconnected from the machine via a connection system (chuck) and self aligns (alignment system of a lithographic apparatus).

Claims 1-5, and 9-16 are rejected under 35 U.S.C. 102(b) as being anticipated by Verbeke et al. (Verbeke) (2003/0045131).

Verbeke discloses an assembly and a method of maintaining a machine part arranged in an interior space (630) of a machine, wherein the interior is kept at a first pressure (para 0073) and is separated from an environment (610) via a load lock (606, 608), the method characterized by transporting a machine part via the load lock out from the interior space; and transporting via the load lock into the interior space, the machine part after being maintained or a separate replacement machine part (para 0073) wherein the apparatus and the load lock are arranged to maintain the first pressure when open to the interior space, and to maintain the second pressure when open to machine part or a separate replacement part (para 0073). Verbeke also discloses cleaning the machine part outside the interior part (200, para 0050). Verbeke discloses the machine which is a lithographic projection apparatus (Fig. 18A, ref 1816) and gripper (1808) arranged to grip and release substrate. Verbeke discloses the machine part (substrate) which is connected to an disconnected from the machine via a connection system (chuck) and self aligns (alignment system of a lithographic apparatus).

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

Claims 6-8, and 17-19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Nakano in view of Miyai et al. (Miyai) (5,825,470).

Nakano discloses the claimed invention as discussed above; however, Nakano does not disclose the machine part which is a substrate table and a pin, which can extend thorough the substrate table to displace the table with respect to the chuck. Miyai discloses transporting a machine part which is a substrate holder (44) from an interior space (12) to an outer environment (14). Therefore, it would have been obvious to one of ordinary skill in the art at the time of the invention to apply the invention of Nakano including the load lock to transporting of the substrate holder from the exposure chamber to the cleaning chamber using the load lock in order to prevent any impurities from entering the exposure chamber as taught by Nakano in para 0010.

Claims 6-8, and 17-19 are rejected under 35 U.S.C. 103(a) as being unpatentable over Verbeke et al. (Verbeke) in view of Miyai et al. (Miyai).

Verbeke discloses the claimed invention as discussed above; however, Verbeke does not disclose the machine part which is a substrate table and a pin, which can extend thorough the substrate table to displace the table with respect to the chuck. Miyai discloses transporting a machine part which is a substrate holder (44) from an interior space (12) to an outer environment (14). Therefore, it would have been obvious to one of ordinary skill in the art at the time of the invention to apply the invention of Verbeke including the load lock to transporting of the substrate holder from the exposure chamber to the cleaning chamber using the load lock in order to prevent exposing the exposure space to the atmosphere of the cleaning space as taught by Verbeke in para 0070-0073.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Peter B. Kim whose telephone number is (571) 272-2120. The examiner can normally be reached on 9:00 AM - 5:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Diane Lee can be reached on (571) 272-2399. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Peter B. Kim/
Primary Examiner, Art Unit 2851

March 31, 2008